

Principles of scanning electron microscopy

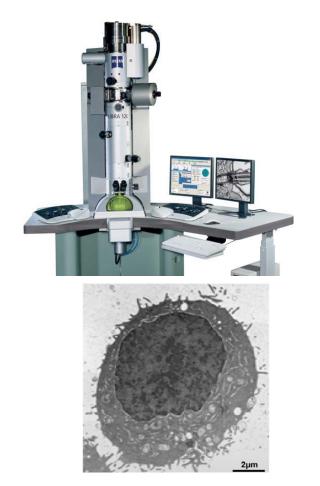
Vladislav Krzyžánek

25th September 2023, Prague course "Advanced Methods of Scanning Electron Microscopy"



Basic types of electron microscopes

Transmission electron microscope (TEM)

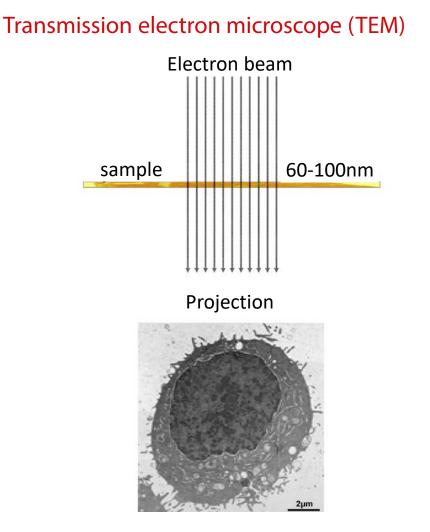


Scanning electron microscope (SEM)

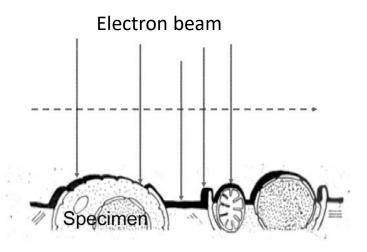


Sorry for missing photos of instruments from Czech companies

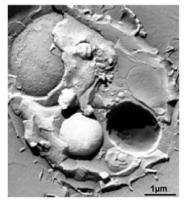




Scanning electron microscope (SEM)



Surface



Typical electron energies: 60 – 300 keV

 \leq 30 keV





- Principle of SEM
- Electron-matter interaction
- Main parts of SEM
- Types of detectors, their usage
- Other configurations
- Multimodal imaging
- Conclusion



Principle of SEM

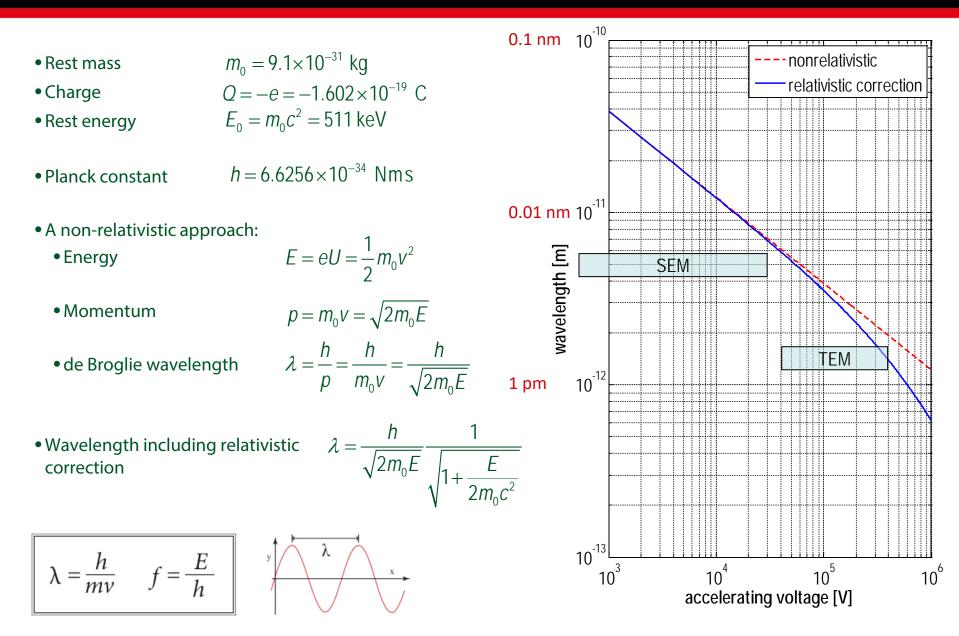
How SEM works

Electron gun



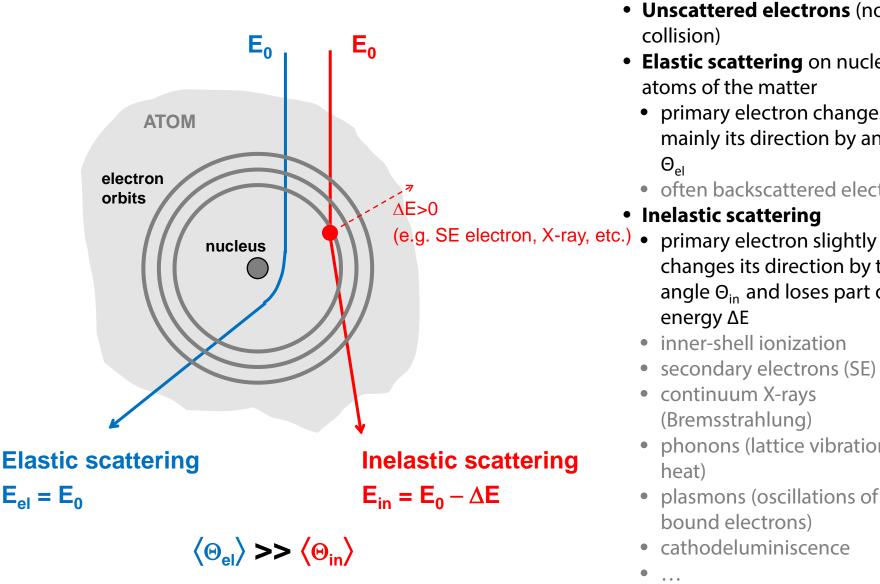


Electrons





How do electrons interact with matter

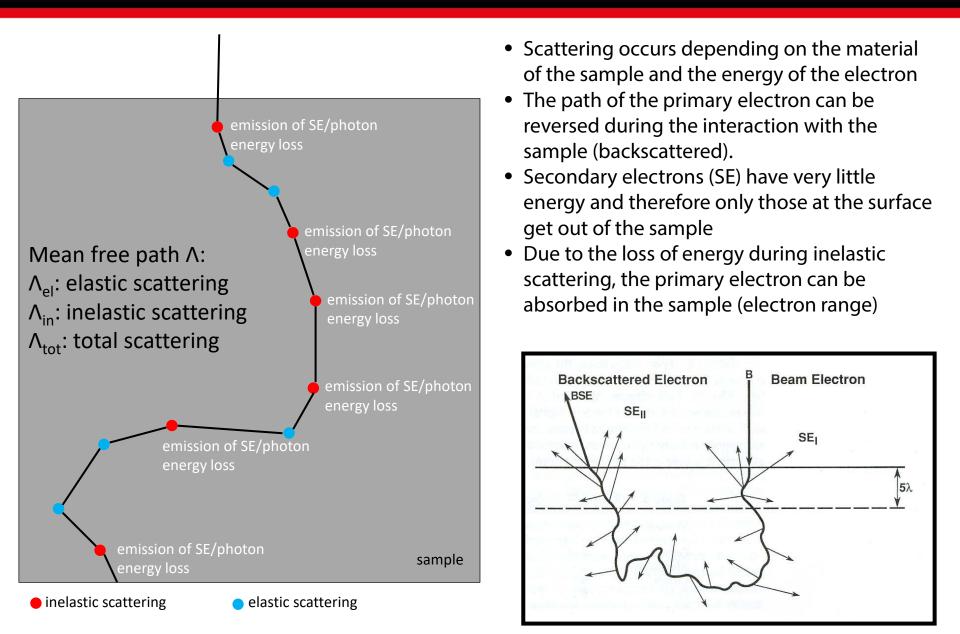


- Unscattered electrons (no collision)
- Elastic scattering on nuclei of atoms of the matter
 - primary electron changes mainly its direction by an angle $\Theta_{\rm el}$
 - often backscattered electrons
- Inelastic scattering
 - changes its direction by the angle Θ_{in} and loses part of its energy ΔE
 - inner-shell ionization
 - secondary electrons (SE)
 - continuum X-rays (Bremsstrahlung)
 - phonons (lattice vibrations heat)
 - plasmons (oscillations of loosely bound electrons)
 - cathodeluminiscence

. . .



Usually multiple scatter occurs



Electron scattering: atomic number and energy

Table 3.1. Total elastic cross-sections $\sigma_{\rm el}$ in units 10^{-16} cm², elastic mean-freepath length $\Lambda_{\rm el} = 1/N\sigma_{\rm el}$ in nanometres ($N = N_{\rm A}\rho/A$: Number of atoms per unit volume), total mean-free-path length $\Lambda_{\rm t} = \Lambda_{\rm el}/(\nu + 1)$ with $\nu = \sigma_{\rm inel}/\sigma_{\rm el}$ and the electron range R in μ m for different elements and electron energies E = 1-50 keV

E [keV]		1	5	10	20	30	50	
C Z = 6	$\sigma_{ m el}$	0.65	0.11	0.055	0.027	0.018	0.012	$\times 10^{-16} \mathrm{~cm}^2$
$\rho = 2 \text{ g/cm}^3$	$\Lambda_{\rm el}$	1.5	9	18	37	55	83	nm
$\nu \simeq 3$	Λ_{t}	0.4	2.3	4.5	9	14	20	nm
	R	0.033	0.49	1.55	4.9	9.7	22.6	$\mu { m m}$
Al Z=13	$\sigma_{ m el}$	1.26	0.31	0.16	0.08	0.053	0.034	$\times 10^{-16} \mathrm{~cm}^2$
$ ho = 2.7 \ { m g/cm^3}$	$\Lambda_{ m el}$	1.3	5	10	21	31	49	nm
$\nu \simeq 1.5$	$\Lambda_{ m t}$	0.5	2	4	8	12	20	nm
	R	0.025	0.36	1.14	3.6	7.1	16.7	$\mu { m m}$
Cu Z=29	$\sigma_{ m el}$	1.84	0.64	0.37	0.21	0.15	0.11	$\times 10^{-16} \mathrm{~cm}^2$
$ ho = 8.9 \ { m g/cm^3}$	$\Lambda_{\rm el}$	0.64	1.8	3.2	5.6	7.8	10.7	nm
$\nu \simeq 0.6$	$\Lambda_{ m t}$	0.4	1.1	2.0	3.5	4.9	6.70	nm
	R	0.007	0.11	0.35	1.10	2.26	5.1	$\mu { m m}$
Ag $Z=47$	$\sigma_{ m el}$	3.09	1.15	0.71	0.43	0.32	0.22	$\times 10^{-16} \text{ cm}^2$
$ ho = 10.5 \text{ g/cm}^3$	$\Lambda_{\rm el}$	0.5	1.5	2.4	4.0	5.3	7.7	nm
$\nu \simeq 0.4$	$\Lambda_{ m t}$	0.4	1.0	1.7	2.8	3.8	5.5	nm
	R^{-}	0.006	0.09	0.29	0.93	1.8	4.3	$\mu { m m}$
Au Z=79	$\sigma_{ m el}$	3.93	1.60	1.05	0.67	0.52	0.37	$\times 10^{-16} \mathrm{~cm}^2$
$ ho = 19.3 \ { m g/cm^3}$	$\Lambda_{\rm el}$	0.43	1.0	1.6	2.5	3.3	4.6	nm
$ u \simeq 0.2 $	$\Lambda_{ m t}$	0.36	0.9	1.3	2.1	2.7	3.8	nm
	$\stackrel{\sim}{R}$	0.003	0.05	0.17	0.51	1.0	2.3	$\mu \mathrm{m}$

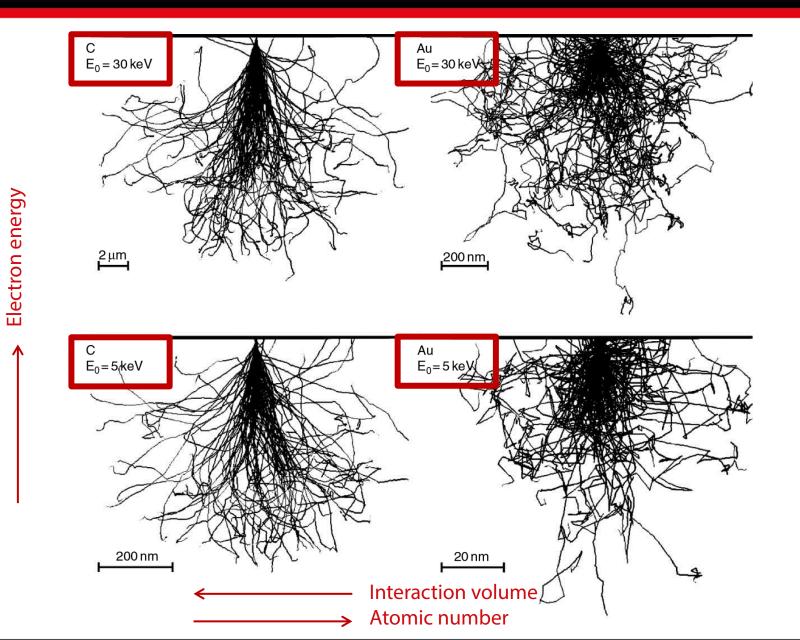
A increases with decreasing Z

 Λ increases with increasing E



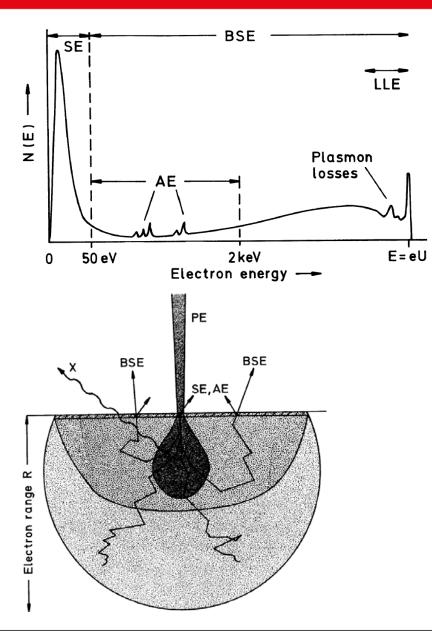
Interaction volume

Monte Carlo simulations of electron scattering





Spectrum of signal electrons



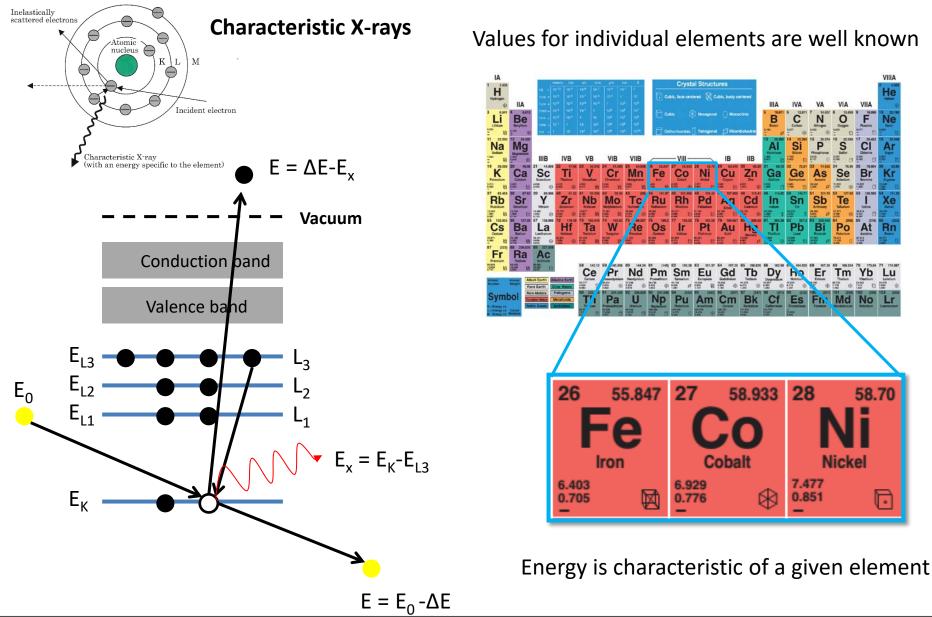
Schematic energy spectrum of emitted electrons consisting of

- secondary electrons (SE; $E_{SE} \le 50 \text{ eV}$)
- backscattered electrons (BSE; E_{BSE} > 50 eV)
- and more signals like Auger electrons (AE) or low-loss electrons (LLE) used mainly for material science

Origin and information depth of

- secondary electrons (SE)
- backscattered electrons (BSE)
- Auger electrons (AE)
- X-ray quanta (X)
 in the diffusion cloud of electron range R for normal incidence of the primary electrons (PE)

X-rays: Energy dispersive X-ray spectroscopy (EDX)



Values for individual elements are well known

VIIIA

Xe

Rn

S

Ge

Sn

Pb

ha Er

28

7.477

0.851

Sb

Bi

Fn

S CI

Se

Po

Tm

Md

Nickel

Br

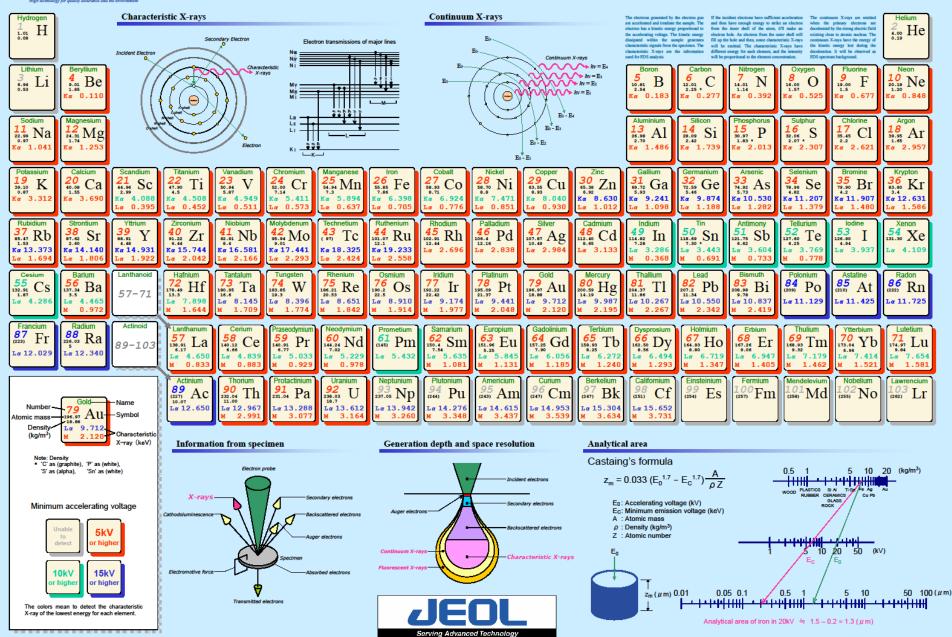
At

58.70



Energy table for EDS analysis

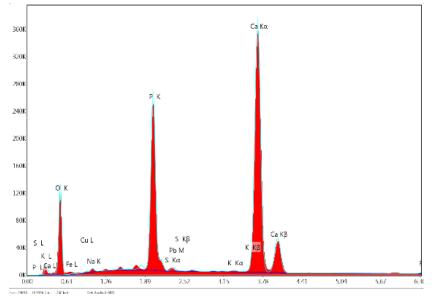
http://www.jeol.com/



JEC6101C602A Printed in Japan

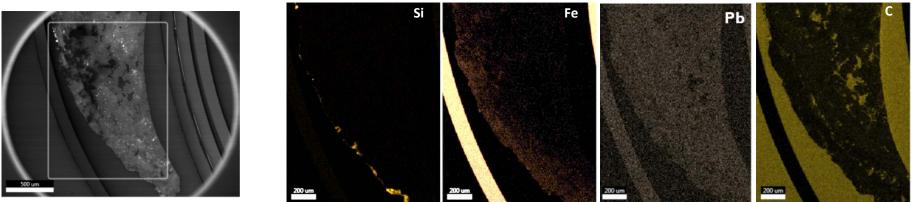
X-rays: Energy dispersive X-ray spectroscopy (EDX)

EDX spectrum recorded from an area or point = all elements in one place



Element	Wt%	Atomic %	6 Error %	Net Int.	Net Error %
OK	42.04	63.00	9.71	368.04	0.13
Na K	0.60	0.63	9.20	15.80	1.28
ΡK	15.20	11.76	2.79	1119.15	0.08
SK	0.06	0.04	10.32	3.98	7.24
Pb M	0.57	0.07	5.27	17.70	2.23
КК	0.13	0.08	7.62	8.86	5.97
Ca K	39.54	23.65	1.53	2026.68	0.05
Fe K	1.44	0.62	2.70	33.46	1.04
Cu K	0.42	0.16	6.01	6.04	4.37

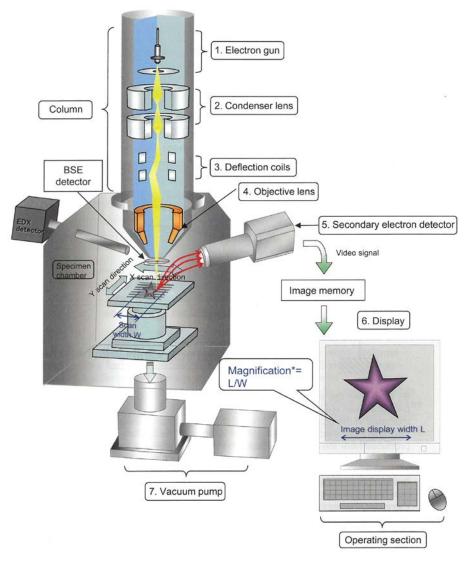
Color representation of selected elements in the sample = one element in all pixels



WDX/WDS: wavelength dispersive X-ray spectroscopy (much better energy resolution, but slow)



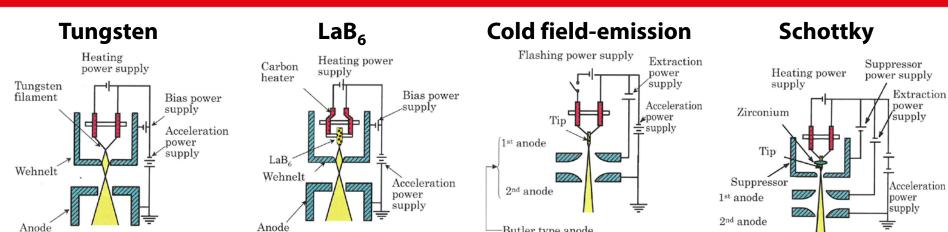
Scanning electron microscope (main parts)



- Electron gun is source of electrons with required parameters
- Condenser lens converge the electron beam emitted from electron gun into finer beam
- Deflection coils are used to scan the electron beam in X and Y directions and change size of the area to be scanned (magnification)
- Objective lens converges electron beam into a fine beam and focus it on the sample surface.
- Detectors for capturing signal for each pixel
- Synchronization of data acquisition and scanning system to receive an 2D image



Kinds of electron guns

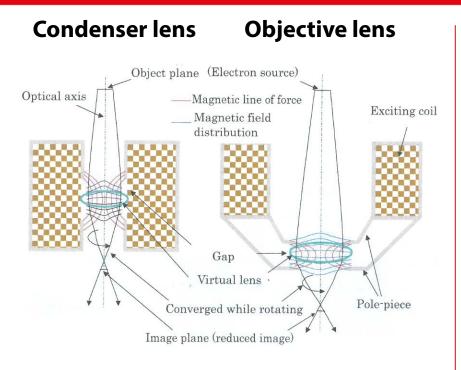


	Tungsten	LaB ₆	CFE	Schottky
Material	Tungsten hairpin	Lanthanum hexaboride single crystal	Tungsten single crystal	Tungsten single crystal/ zirc. oxide
Cathode temp	~2300 °C	~1500 °C	RT °C	~1500 °C
Brightness	10 ⁶ A/cm ² ⋅sr	10 ⁷ A/cm ² ·sr	10 ⁹ A/cm ² ·sr	10 ⁸ A/cm ² ·sr
Energy width	~2 eV	~1.5 eV	0.2-0.3 eV	0.3-1 eV
Max. probe current	~100 nA	~100 nA	~10 µA	~100 nA
Working pressure	10 ⁻⁴ Pa	10 ⁻⁵ Pa	10 ⁻⁸ Pa	10 ⁻⁷ Pa
Lifetime	50-100 h	200-1000 h	2-4 y	2-3 у

Butler type anode

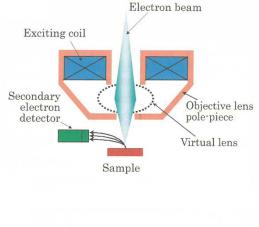


Electron lenses

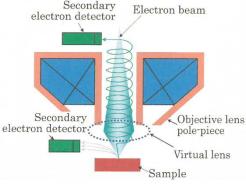


Electron lenses in SEM: magnetic/electrostatic lenses to focus the accelerated virtual electron source from electron gun into a fine probe onto the sample surface.

Condenser lens: "shaping" electron beam (responsible for its intensity) **Objective lens:** focusing the electron beam into a fine probe



Secondary electron detector Virtual lens Virtual lens Sample Objective lens pole-piece



Standard type

- generally used in low-end SEM
- WD can be high (longer depth of focus)
- optionally can be set also in snorkel type

In-lens type

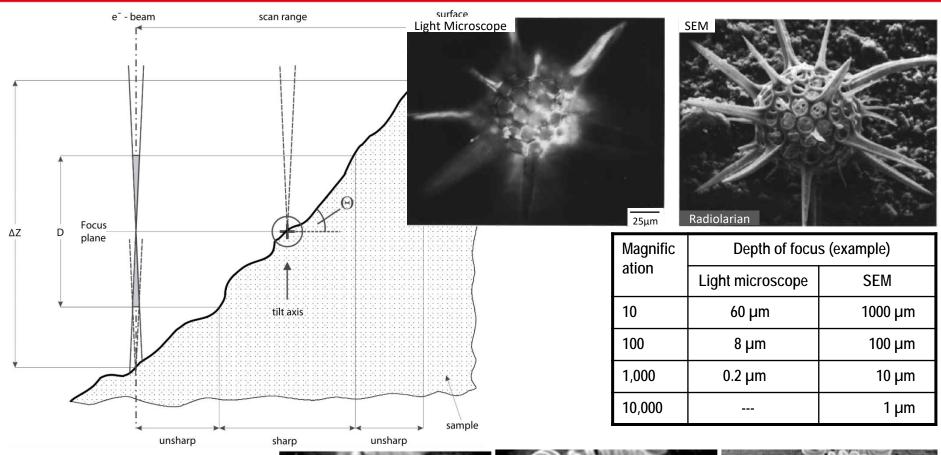
- best resolution SEM
- only short WD
- limited sample size

Semi in-lens (snorkel) type

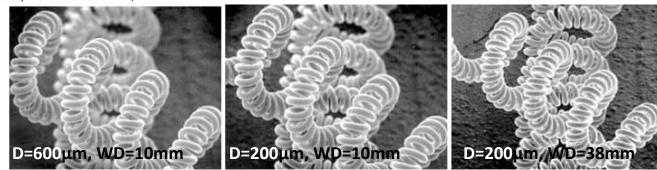
- high-end SEM
- virtual lens close to sample (sample in EM field)



Depth of focus in SEM

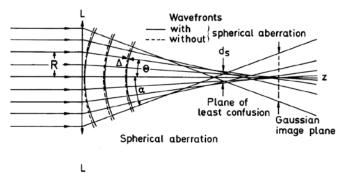


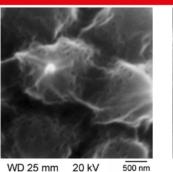
Effect of aperture diameter (D) and working distance (WD) of depth of focus (Light bulb coil)

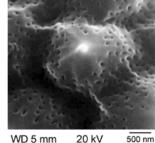




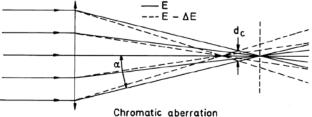
Lens aberrations

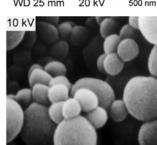




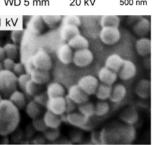


 $d_{s} \sim \frac{1}{2} C_{s} \alpha^{3}$ C_s ... spherical aber. coef.

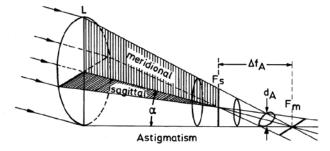


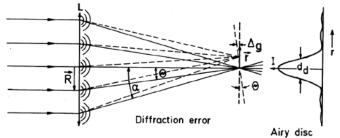


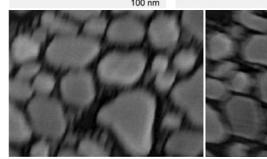
100 nm

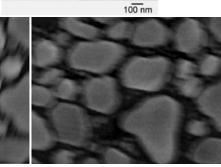


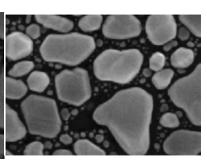
 $d_{c} \sim C_{c} (\Delta E/E_{0}) \alpha$ C_c ... chromatic aber. coef.





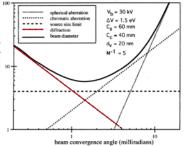






 $d_d = 1.22 \lambda/\alpha$ λ ... wavelength of electrons

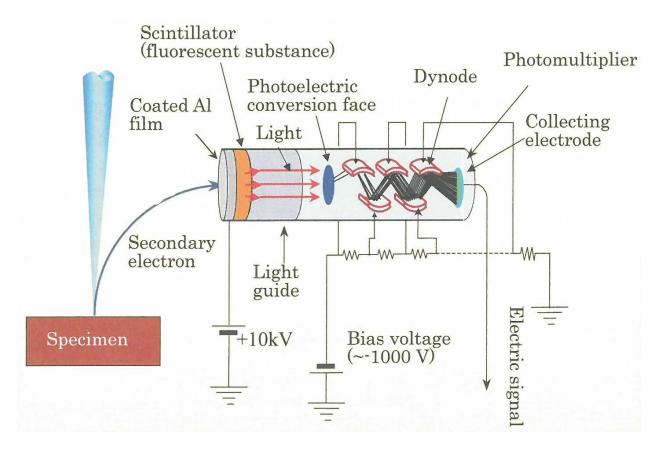
Increasing α effects spherical and chromatic aberrations being higher





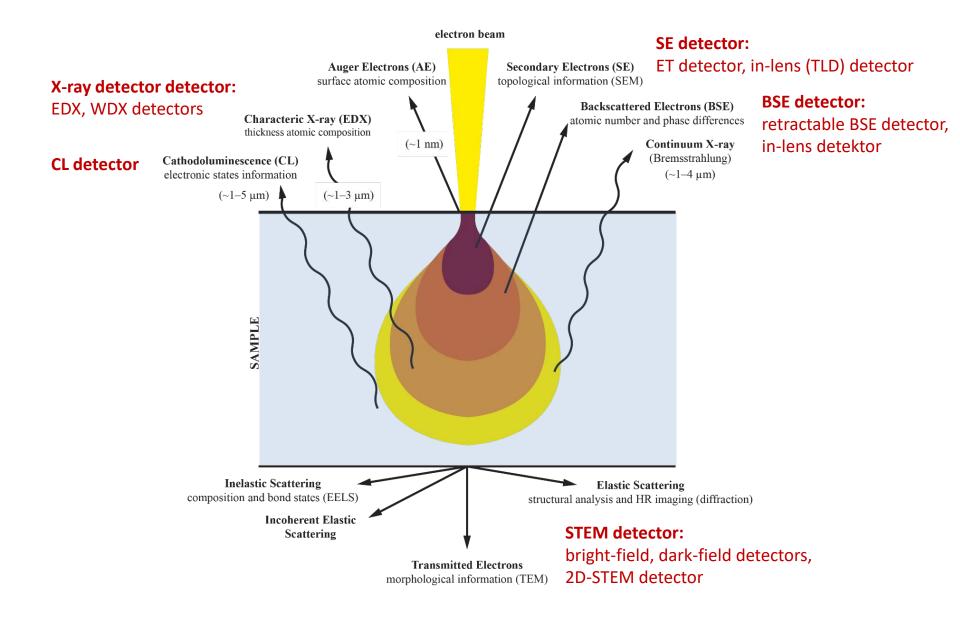
Everhart-Thornley (ET) detector

• SE electrons (very low energy <50 eV) are accelerated towards 10 kV electric field and hit against the scintillator for conversion into the light signal which leads to the photomultiplier tube (PMT) through a light pipe





Signals in SEM and their detection



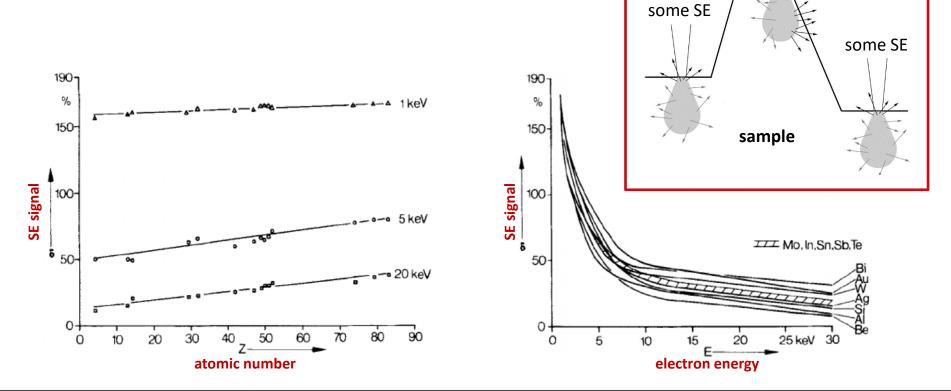


Edge effect

many SE

SE signal:

- is formed by very low energy of secondary electrons (≤ 50 eV) generated from the collision between the primary electrons and loosely bound outer electrons
- gives mainly information about topography (topographic contrast), less about composition
- increases with decreasing electron energy
- weaker dependence on atomic number Z
- is strongly dependent on tilt of the sample (edge effect)

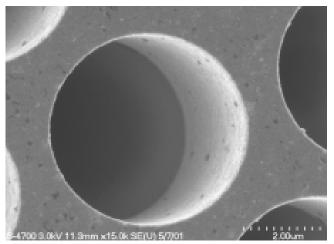




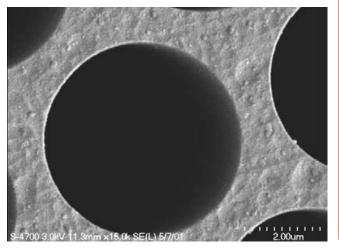
Secondary electrons (SE)

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- SE detector type
- upper "in lens" detector



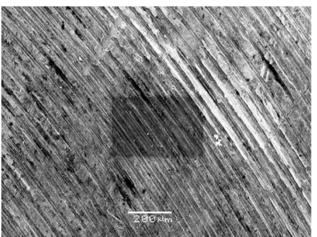
• lower "ET" detector



- Artefacts
- charging



contamination

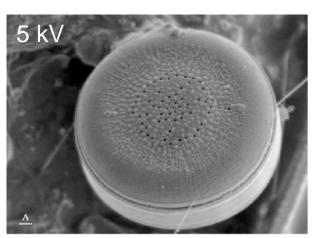


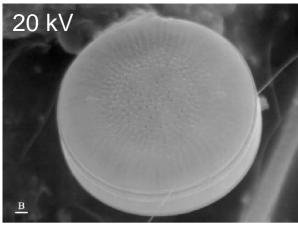
- In non-conducting samples the electron probe current remains in sample \rightarrow accumulation of charge \rightarrow artefacts mainly for SE (reducing probe current, lowering E_{o} , imaging with BSE, metal coating,...)
- Result of interaction of electron beam with residual gasses and hydrocarbons on the sample surface (ensure cleanliness, decrease probe current, use plasma cleaner,...)



Secondary electrons (SE)

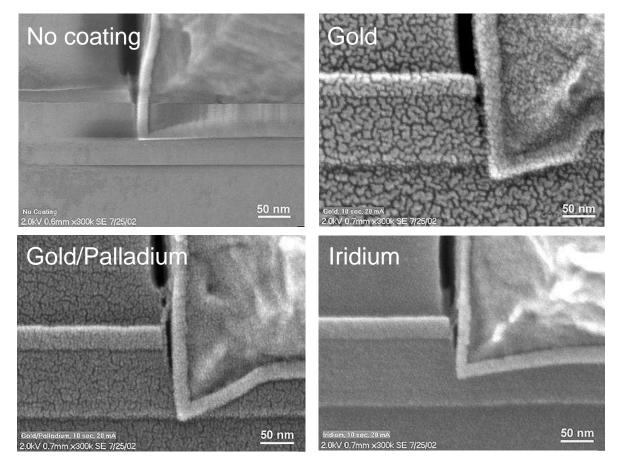
• Effect of penetration depth





Bar: 1 µm (Sample: Diatom)

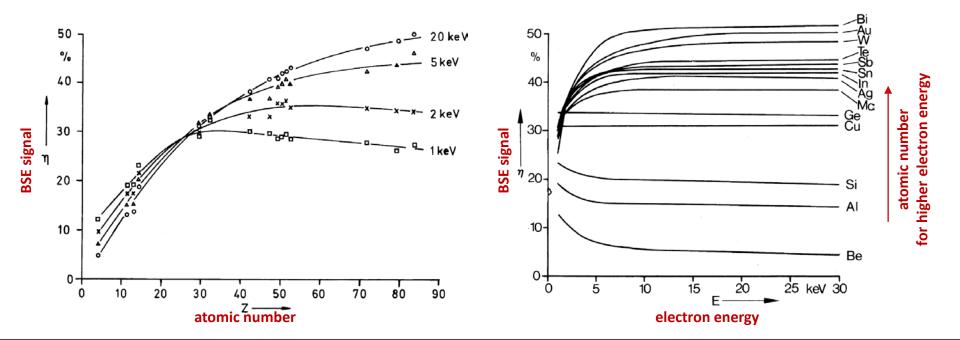
- Enhancement of contrast by metal coating to reduce
 - Interaction volume
 - Charging effect
 - Beam damage





BSE signal:

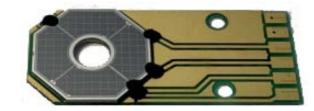
- is formed by primary electrons which are backscattered (all electrons in the energy range from 50 eV to E₀)
- in general number of BSEs is much lower than SEs
- gives mainly information about material (material contrast), less about topography
- increases with increasing atomic number Z up to $E_0 \sim 30$ keV
- increases with increasing tilt of the sample
- is almost independent on energy for E₀ >10 keV



Backscattered electrons (BSE)

- BSE detector type
- retractable BSE detector (standard BSE like ET for SE)
- annular active area (well defined)
- very effective
- basic types
 - scintillator based (usually YAG detector)
 - usually 1 segment
 - semiconductor detector
 - usually multi-segment

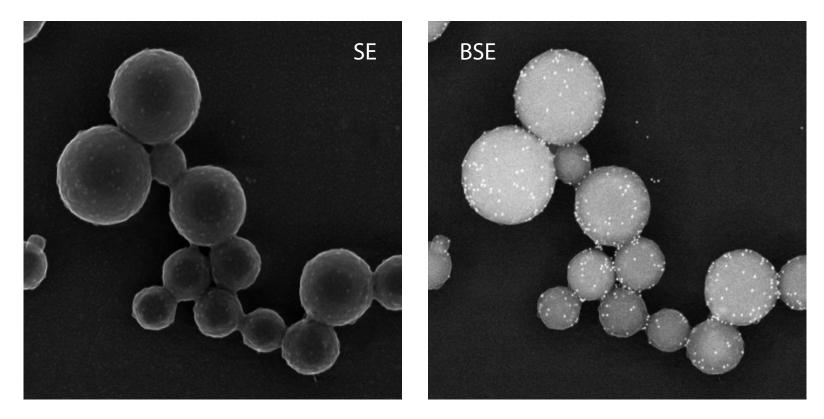




- in-lens detector (only for snorchel type objective)
 - various possibilities depending on SEM producer and SEM type



• Immunogold labeling of surface proteins (rubber nanoparticles isolated from *Taraxacum*)

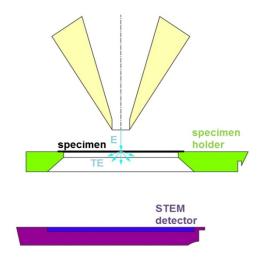


SE: sample surface information (topography)

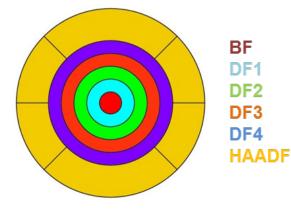
BSE: due to targeted immunolabeling (gold nanoparticles bound to immunoglobulin) the possibility to identify specific parts on the sample (bright Au nanoparticles)

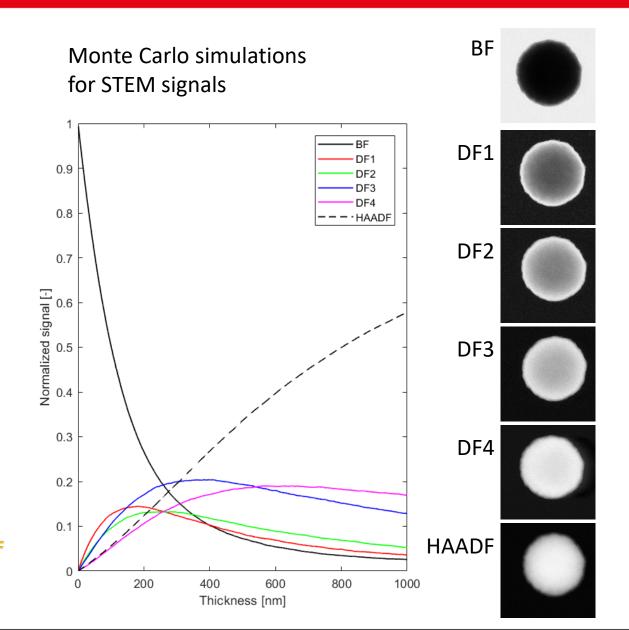


STEM: Scanning Transmission Electron Microsc.

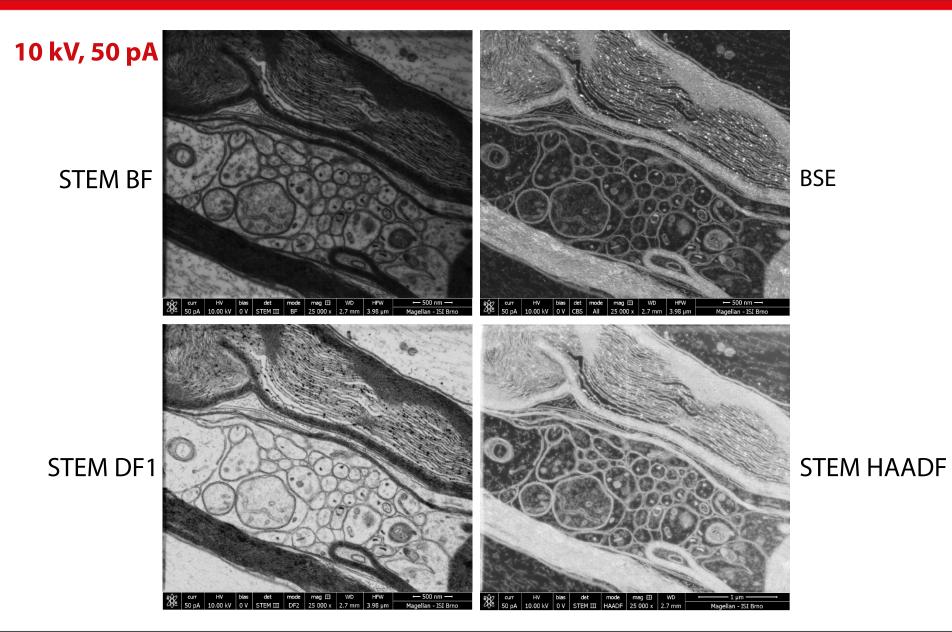


Multisegment STEM detector





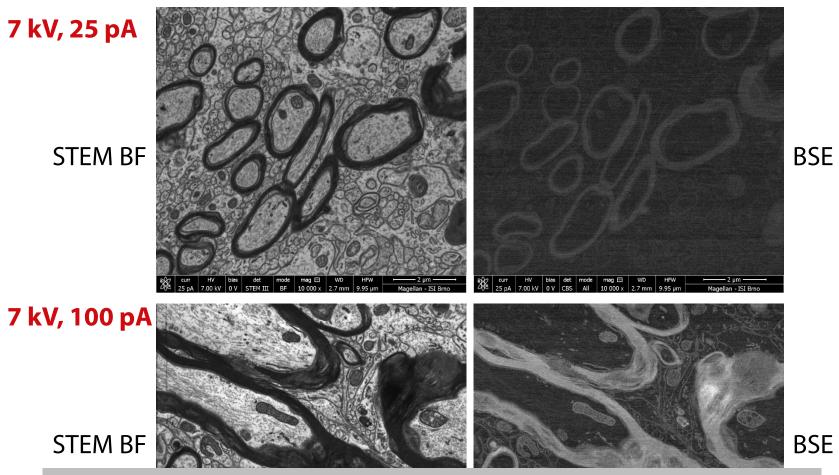




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STEM vs. BSE



STEM-in-SEM

- can be used for imaging of ultrathin sections like TEM (less comfortable)
- can be used as imaging without need of staining, see Microorganisms 11 (2023), 888

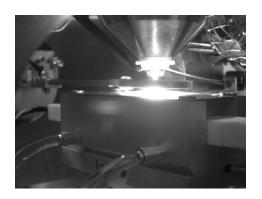


ESEM (Environmental SEM)

- specimen chamber pressure up to 3000 Pa (various gasses possible)
- different detectors required
- convenient for insulating samples, vacuum sensitive samples (biological),...

in-situ SEM, cryo-SEM

- hot stage / mainly for material sci.
- cryo-stage / mainly for life science

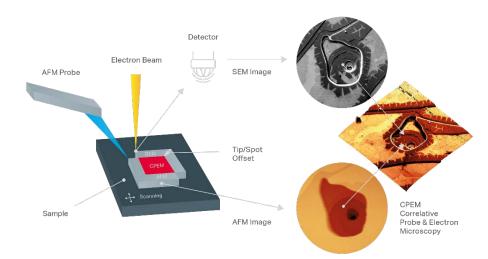


FIB-SEM, SBF-SEM

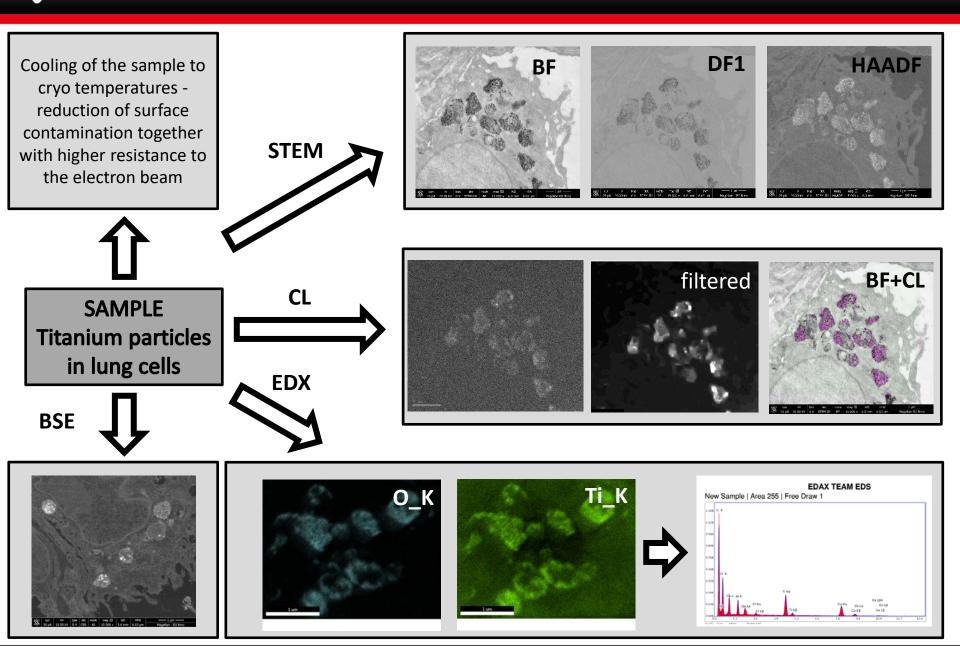
- focused ion-beam implemented into SEM
- ultramicrotome implemented into SEM
- \rightarrow see another lecture

Combination with AFM

integration of AFM into SEM



Multimodal imaging (correlative imaging)





- SEM is a versatile instrument that can be used for many purposes and can be equipped with various accessories
- Secondary electrons (SE): mainly topography
- Backscattered electrons (BSE): mainly material contrast
- Transmitted electrons (STEM): mass-density contrast
- X-ray: chemistry (composition)
- Use the full power of your SEM play around with the settings (modern SEMs offer many options)
- EM manufactures:

















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- There are more free programs, e.g.
- CASINO "monte CArlo SImulation of electroN trajectory in sOlids" <u>https://www.gegi.usherbrooke.ca/casino/</u>
 - Version 2 is simple for users (only films) ... recommended for beginners
 - Version 3 works in 3D (user-defined shapes) ... more complicated
- Movie in Czech: Kukátko do nanosvěta z cyklu NEZkreslená věda <u>https://youtu.be/2vYquoVWLqQ</u>